



33082M172

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants : Takanori Mimura, et al.  
Serial No. : 10/647,433 Art Unit : 1765  
Filed : August 26, 2003 Examiner : Binh X. Tran  
For : SILICON ETCHING METHOD

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:


Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicants enclose an Information Disclosure Citation Form (PTO-1449).

It is respectfully requested that the cited documents be considered by the Examiner in the above-identified patent application and that the cited documents be made officially of record therein. It is further requested that a listing of the same appear on the face of any patent which may issue from this application.

No Official Action on the merits yet has issued for this application. In accordance with 37 C.F.R. §1.97, no fee is considered due in connection with the filing of this Statement.

Respectfully submitted,  
SMITH, GAMBRELL & RUSSELL, LLP

By: \_\_\_\_\_

  
Michael A. Makuch, Reg. No. 32,263  
1850 M Street, N.W., Suite 800  
Washington, D.C. 20036  
Telephone: (202) 263-4300  
Fax: (202) 263-4329

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FORM PTO-1449 <b>INFORMATION DISCLOSURE STATEMENT</b>	ATTY. DOCKET <b>033082.172</b>	SERIAL NO. <b>10/647,433</b>
	APPLICANT: <b>Takanori Mimura, et al.</b>	
	FILING DATE <b>8/26/03</b>	GROUP ART UNIT <b>1765</b>

#### U.S. PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE, IF APPROPRIATE
	AA	5,423,941	6/13/95	Komura et al.			
	AB	4,793,897	12/27/88	Dunfield, et al.			
	AC	6,303,512	10/16/01	Laermer et al.			
	AD						

#### FOREIGN PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
	AE						YES	NO
	AF							
	AG							
	AH							
	AI							

#### OTHER INFORMATION (Including Author, Title, Date, Pertinent Pages, Etc.)

	AJ	
	AK	
EXAMINER:		DATE CONSIDERED:
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>		

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